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20	11	(magnet\$6 adj2 junction) and (magnet\$6 same etch\$3)	EPO; JPO; DERWENT; IBM_TDB	2003/07/03 10:30
21	125	(magnet\$6 adj2 junction) and etch\$3	USPAT	2003/07/03 10:30
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1 Fully integrated 64 Kb MRAM with novel reference cell scheme

Jeong, H.S.; Jeong, G.T.; Koh, G.H.; Song, I.H.; Park, W.J.; Kim, T.W.; Jeong, S.J.; Hwang, Y.N.; Ahn, S.J.; Kim, H.J.; Hong, J.S.; Jeong, W.C.; Lee, S.H.; Park, J.H.; Cho, W.Y.; Kim, J.S.; Song, S.H.; Park, S.O.; Jeong, U.I.; Kim, K.;

Electron Devices Meeting, 2002. IEDM '02. Digest. International , 8-11 Dec. 2002

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[\[Abstract\]](#) [\[PDF Full-Text \(359 KB\)\]](#) **IEEE CNF**

2 Barrier formation in lead-based tunnel junctions studied by surface techniques

Emmanuel, A.; Donaldson, G.; Band, W.; Dew-Hughes, D.;

Magnetics, IEEE Transactions on , Volume: 11 Issue: 2 , Mar 1975

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[\[Abstract\]](#) [\[PDF Full-Text \(400 KB\)\]](#) **IEEE JNL**

3 Reactive ion etching in the fabrication of niobium tunnel junctions

Reible, S.;

Magnetics, IEEE Transactions on , Volume: 17 Issue: 1 , Jan 1981

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